



NB Technologies has designed a sealed wafer holder especially for electroplating and wet etching applications in microsystems technology and the semiconductor industry.

Applications

- Wet chemical processes e. g. etching
- Electroplating
- Anodization
- Porosification of silicon

Main benefits

- Single side / backside dry processing
- Front- or backside contact
- Temperature resistant up to 70°C
- Easy handling

For substrates up to 200 mm

Outer dimensions (incl. handle):

- w 198 mm x l 25 mm x h 263 mm
- Weight: 1,34 kg

Different versions for different Wafer geometry:

- 100 mm, 150 mm, 200 mm SEMI standard
- Notch or Flat
- 125 mm PV square
- 156 mm PV square
- Or custom design

Materials:

- PEEK
- EPDM seals
- Titanium contacts

